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Wednesday, August 5, 2020

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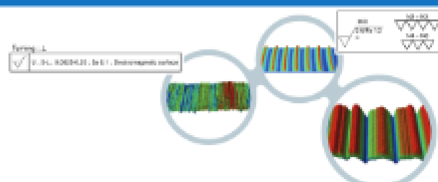

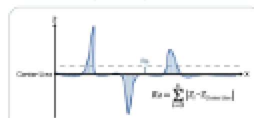

Advantages of Measuring Surface Roughness with White Light Interferometry

This application note discusses the use of mean roughness measurements with white light interferometry (WLI) optical profilers. Spatial filters are explained, as well as some of the normative standards requirements from ASME B46.1-2009, ISO 13565-12 and JIS B 0671-1. Main technical reasons for WLI selection are covered as well as the advantages and areas of applicability of the full areal measurement standard from ISO 25178-2.

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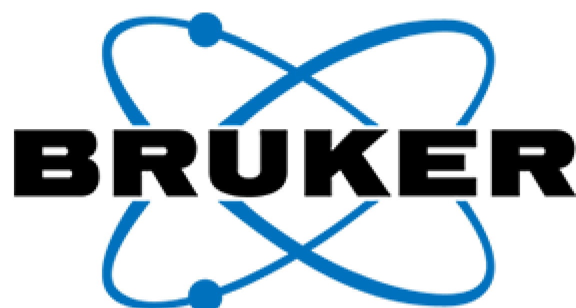

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